

"Extreme Storage Rings" Workshop (ESRW22)



Recent progress on a <u>Steady-State MicroBunching</u> light source at Tsinghua University

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On behalf of the THU SSMB Team

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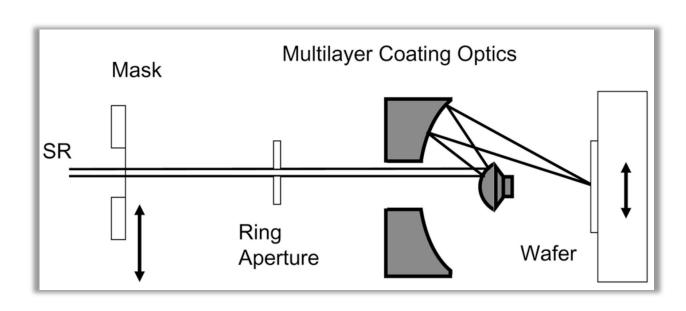
Outline

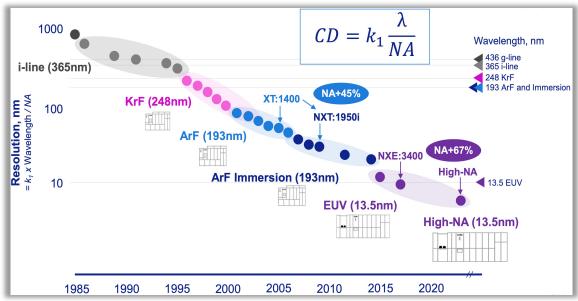
- Introduction
- SSMB mechanism
- SSMB-EUV project
- Summary



Light sources for EUVL

- Shorter wavelength and high power radiation highly desirable for lithography
- Lithography R&D using SRs kicked off in 1980s
- Working wavelength for lithography converged to ~13 nm together with optics



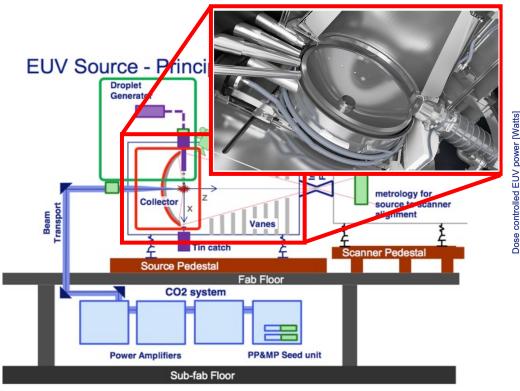


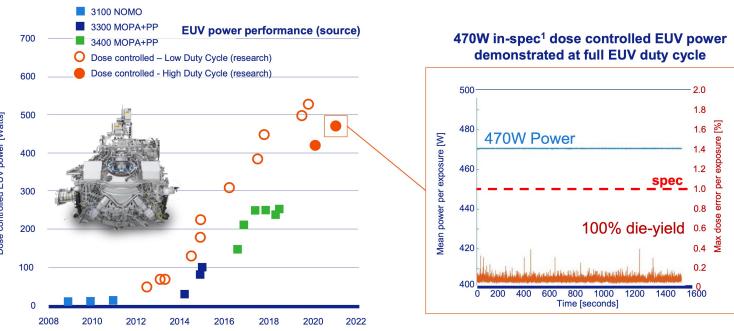
X-ray reduction lithography - H. Kinoshita et al. (1986)

Jan van Schoot et al., 2021 EUVL Workshop



- Laser-produced plasma (LPP) source developed into commercial product
 - High power CO₂ laser drives liquid Sn droplet to generate 13.5 nm light
- Continuing LPP R&D toward higher power (250 W in product and ~500 W demonstrated in lab)



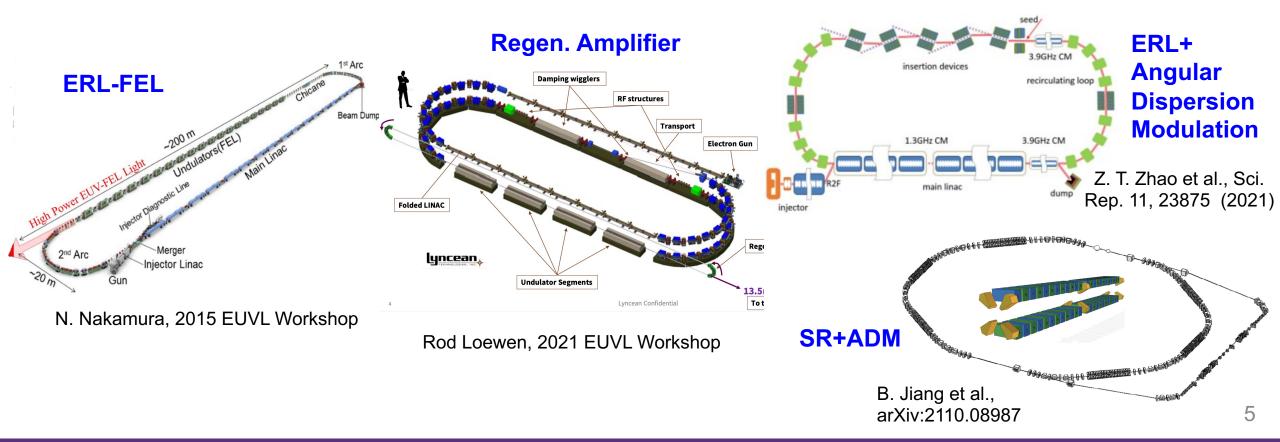


Jan van Schoot et al., 2021 EUVL Workshop



High power accelerator EUV source

- ☐ Accelerator-based EUV source for lithography :
 - Clean, potential for >1 kW, multiple beamlines, extendable to shorter wavelength
 - Cost, scale, temporal structure, matching optics to downstream





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Steady-state Microbunching (SSMB)

 Concept proposed by D. Ratner and A. Chao, PRL 105, 154801 (2010).

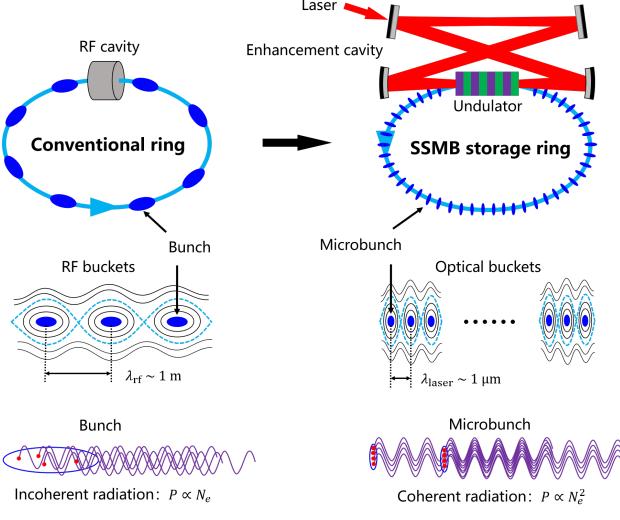
"the microbunching
(MB) is permanent at
the radiator, so we consider this SSMB"

1.9 Lu
(1-1/h)R₅₆

Radiator
Lu
(1/h)R₅₆

- Aiming at combining the high rep-rate of SR and high peak power of FEL
- Using optical cavity replace RF cavity
 + compatible lattice
- Generate high average power, high rep-rate to CW coherent radiation, at wavelengths from THz to EUV even beyond

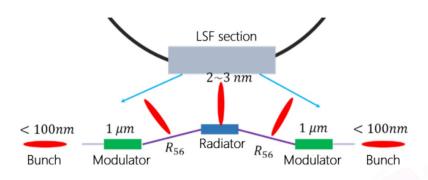
6 orders of magnitude extrapolation

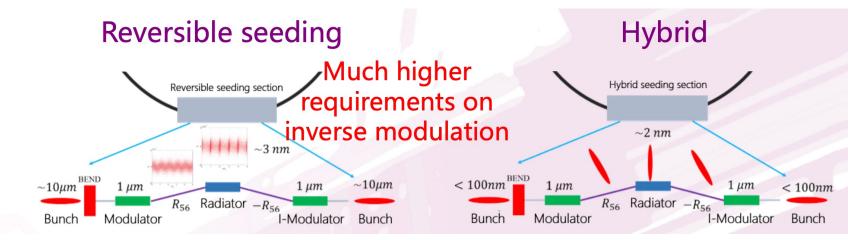




Schemes for high power EUV radiation

Longitudinal strong focusing





- Low-alpha SR (~100 nm bunch) + longitudinal strong focusing (~3nm)
- Required laser power: hundreds MW, pulsed, Duty factor: 1%
- peak power : several kW, average power : several tens W

- Regular SR + ADM compression (~3nm)
- Required laser power: ~1 MW
- Low bunching factor, coasting beam (@10A)
- Average power : ~ kW

- Low-alpha SR (~100 nm bunch) + ADM compression (~3nm)
- Required laser power: ~1 MW
- high bunching factor
- Average power : ~ kW (@1A)



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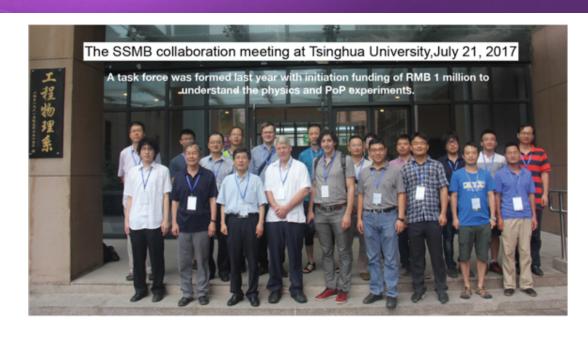


SSMB taskforce at Tsinghua

- Kick-off meeting in July 2017 with colleagues from China, Germany, France, U.S., South Korea etc.
- R&D on SSMB physics, technologies and a research facility
- Supported by Tsinghua University Initiative Scientific Research Program and NSFC

First SSMB Light Source Workshop (Online), Dec. 7-9, 2021 80+ participants from 20 institutes worldwide







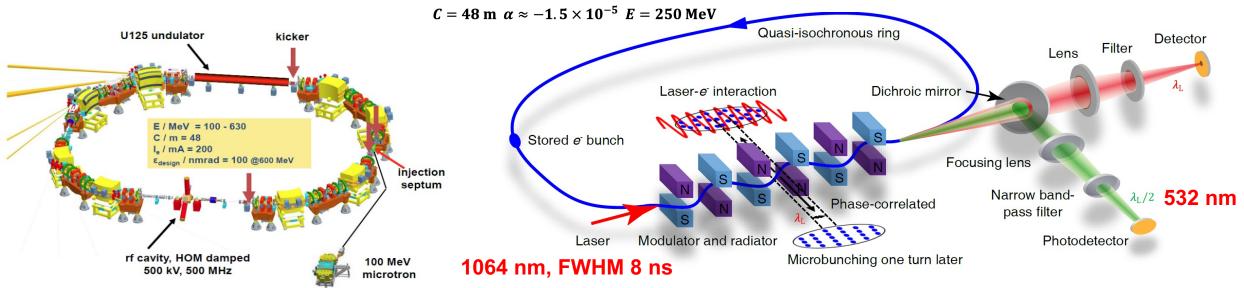




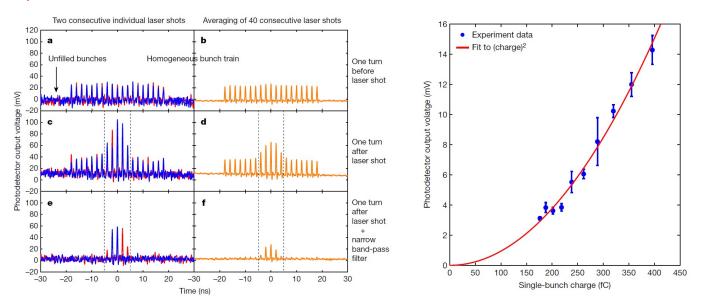




Proof-of-principle experiment



- Phase I Goal: generate and maintain MB for at least one turn
- Modulate once, observe CSR afterwards
- Collaboration with HZB & PTB
- Experiment carried out at MLS

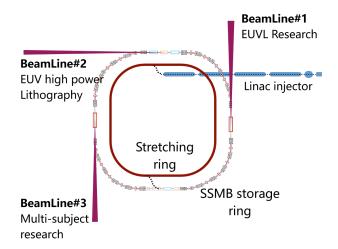




Proof-of-principle experiment

Article Experimental demonstration of the mechanism of steady-state microbunching https://doi.org/10.1038/s41586-021-03203-0 Xiujie Deng¹, Alexander Chao^{2,3}, Jörg Feikes⁴, Arne Hoehl⁵, Wenhui Huang¹, Roman Klein⁵, Arnold Kruschinski⁴, Ji Li⁴, Aleksandr Matveenko⁴, Yuriy Petenev⁴, Markus Ries⁴, Received: 27 March 2020 Chuanxiang Tang^{1™} & Lixin Yan¹ Accepted: 7 January 2021 Published online: 24 February 2021 The use of particle accelera News & views Check for updates and technology1. Currently synchrotron radiation faci **Experimental physics Accelerator-based light** sources get a boost Electron bunch **Alexander Brynes** The structure of matter can be explored using the light emitted by particle accelerators. An experiment demonstrates how the properties of two such light sources – synchrotrons and free-electron lasers – can be combined. See p.576 over unprecedentedly short scales of length After one turn and time. On page 576, Deng et al. report a proof-of-principle experiment on an accelerator that could extend the capabilities of these machines even further, potentially yielding applications in a next-generation chip-etching technology called extreme-ultraviolet lithography² and an advanced imaging method known as angle-resolved photoemission spectroscopy³. Accelerator Path of

- Phase I: MB at long wavelength can be created and maintained for one or few turns
- Phase II: modulate thousands of turns, maintain MB each turn
- Laser and diagnostics are being tested
- Scheduled beamtime in 2022
- Phase III: dedicated SSMB research facility for true SSMB, keep MB to steady-state



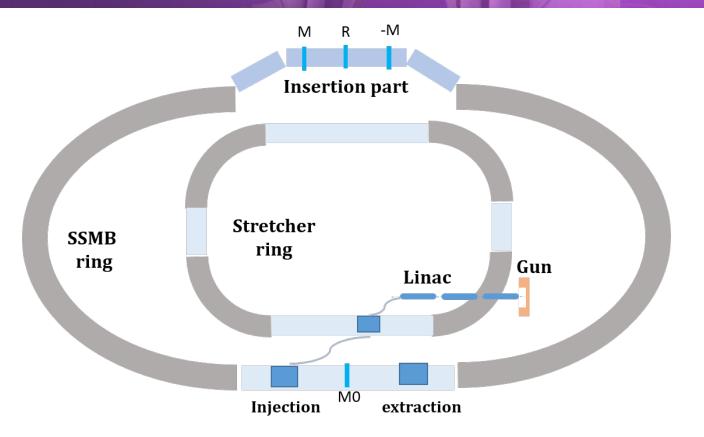
- A dedicated SSMB EUV research facility under design and study at Tsinghua
- For studying SSMB physics and provide 3 beamlines for EUV and EUVL research

Deng, X. et al., Nature 590, 576 (2021).

electron bunch



THU SSMB-EUV light source project

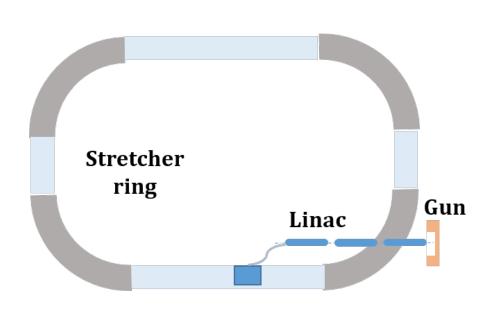


Parameters	Value	Units
Circumference	138.43	m
Beam energy	400	MeV
Tunes (x/y)	0.23/0.21	
α_c	-4.05×10^{-6}	
Damping time (x/y/z)	539.9/542.1/271.6	ms
Energy spread	1.91×10^{-4}	
Natural emittance	181.5	pm
Bunch length	74.1	nm

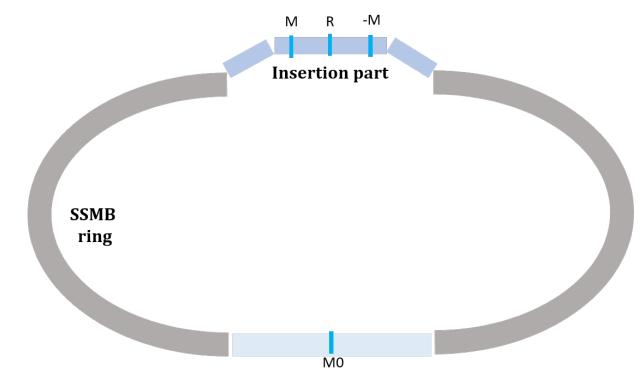
- Injector based on a photocathode rf gun in marco-pulse mode at ~1 A beam current
- Accelerated to 400 MeV (strong beam-loading) and then stretched by the stretcher ring (large R₅₆) for about 200 turns to a CW coasting beam
- Injected into SSMB main ring, compressed to ~3 nm, and generate kW EUV radiation



THU SSMB-EUV light source project



- □ Completed initial linac and stretcher ring design, the energy spread of coasting beam can be below 0.05% (control the beam loading effects)
- ☐ Top-up injection scheme being considered, to maintain the stability of EUV power

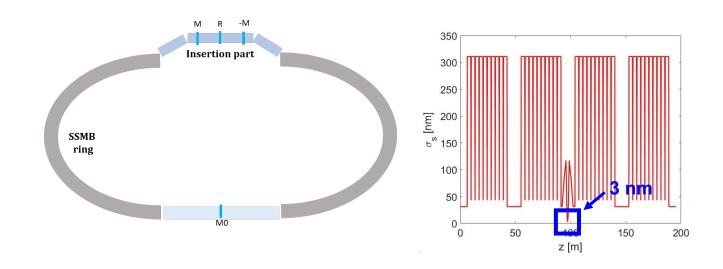


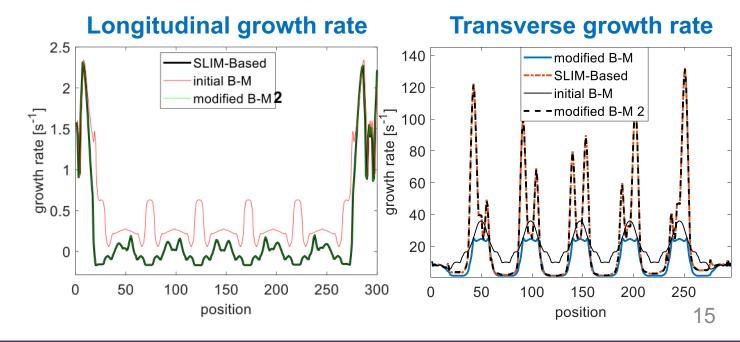
- □ Completed initial main ring design, the bunch length can be maintained at less than 100 nm.
- □ hybrid insertion option, electron bunches can be compressed to 3 nm and generate > 1kW power
- Multi-particles effects are being studied, nonlinear optimization is on going



IBS effects in SSMB

- In a SSMB SR, electron beams contain fine structures - nm beamlets with um spacing, at low emittance and relatively low beam energy
- Bunch length of nm beamlets vary significantly along the ring
- A new code is under development to calculate IBS growth rate for SSMB – taking into account longitudinal beam dynamics and T-L coupling
- Lattice optimization with IBS effects included is on-going



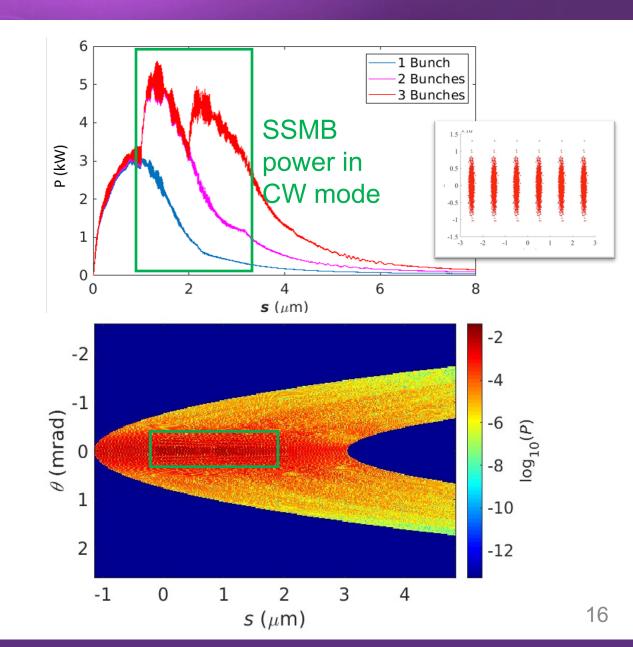




Calculate EUV radiation property

Paras.	Hybrid	LSF
Ratio	40%	41%
Power (W)	4200	3292
Mode	CW	Pulsed (Duty factor: 1%)

- Modulation laser wavelength: 1 um, so is the beamlet separation
- The radiation will be CW
- Narrow band, N_u ~ hundreds

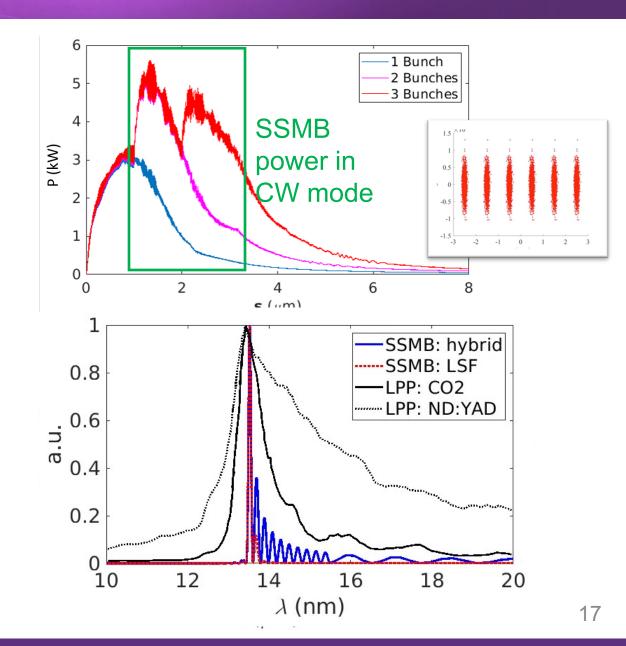




Calculate EUV radiation property

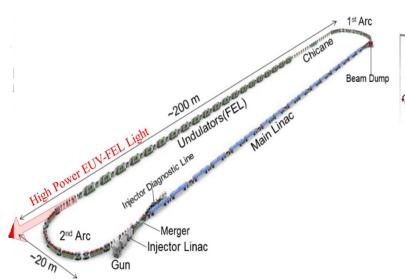
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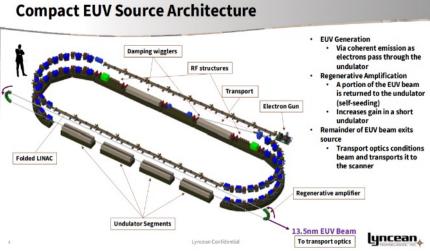
- Modulation laser wavelength: 1 um, so is the beamlet separation
- The radiation will be CW
- Narrow band, N_u ~ hundreds





Comparison with other schemes





BeamLine#2
EUV high power
Lithography

Stretching
ring

SSMB storage
ring

Multi-subject
research

SSMB

SSMB

ERL-FEL

- ~hundreds meter undulator
- Super-conductivity linac
- average power : ~kW to 10kW
- Test facility commissioning

Regen. Amplifier

- ~tens meter undulator
- Ring-based, strong damping
- Optical cavity at 13.5 nm
- average power : ~kW
- Conceptual design

- ~several meter undulator
- Ring-based, steady-state
- average power : ~kW
- Conceptual design



Key technology - optical cavity

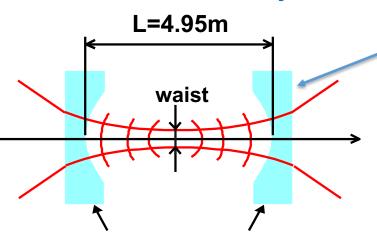


Test bench for a highpower two- mirror optical cavity experiment

SLS 超腔 PDH 反馈

Cavity parameters

Two-mirror optical enhancement cavity



	CVBG λ 4 PBS λ 2 FI λ 2 LO
波荡器 M2 M1 BS 二镜光学增益腔	ル2 EOM 光纤放大器 Telescope

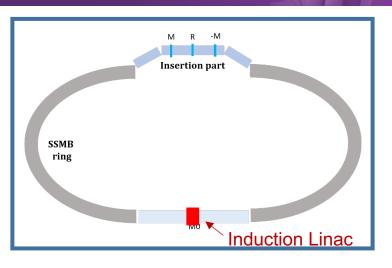
PDH 反馈

- The two-mirror test system has been set up
- Phase I: 10 kW average power, ongoing
- Phase II: 1MW average power

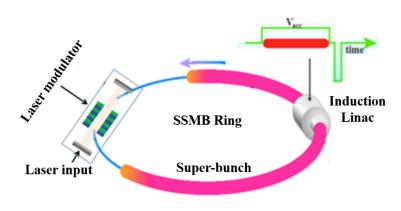
Parameters	Design specs
wavelength	1064 nm
configuration	Two-mirror
cavity length	4.95 m
operation mode	CW mode
average power	~1 MW
Q	~10000
input laser power	130 W



Key technology - induction linac



—— the synchrotron radiation loss will be compensated for by the induction linac



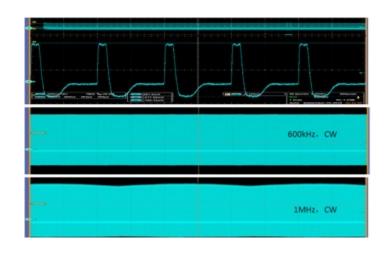
- A prototype cavity has been built and tested
- Achieved 1 MHz repetition rate, 1
 kV voltage, with 100 ns flap top



Prototype of induction Linac



High repetition rate test



Pulse type in High repetition rate mode 39



- SSMB is a unique and new concept light source, with potential to produce kW EUV power at relatively low cost
- Very challenging as well as interesting physics and technologies
- The POP: Phase I for SSMB completed successfully with collaborators, and Phase II is underway – laser, diagnostics and e-beam preparation
- A SSMB EUV light source is under study at THU physics, key techniques and design of a research facility - aiming at kW EUV output
- Will benefit tremendously from discussion, suggestion, and collaboration

Thank you for your attention!